



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Basol et al.  Serial No.: 10/654,542  Filed: September 2, 2003  Title: Constant Low Force Wafer Carrier For Electrochemical Mechanical Processing And Chemical Mechanical Polishing	Group Art Unit: 1753 Examiner: Not yet assigned Docket: NT-260 -US
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**INFORMATION DISCLOSURE STATEMENT**

**US PATENT DOCUMENTS**

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant	
EM	AA	6,447,379	Sep., 2002	Gromko et al.	Copy Enclosed
EM	AB	6,443,824	Sep., 2002	Shendon et al.	Copy Enclosed
EM	AC	6,080,050	Jun., 2000	Chen et al.	Copy Enclosed
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**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant		

**OTHER DOCUMENTS**

Examiner Initials	Cite No.			Trans- lation

Examiner Signature	/Eileen Morgan/	Date Considered	06/21/2006
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